

The fabrication of Ti_3C_2 and Ti_3CN MXenes by electrochemical etching

Supporting information

Bragg's law and the reciprocal-space metric tensor equation of hexagonal crystal lattices:

$$n\lambda = 2d\sin(\theta); \quad \frac{1}{d^2} = \frac{4}{3} \left(\frac{h^2 + hk + k^2}{a^2} \right) + \frac{l^2}{c^2}$$

Calculation of charge conducted during the electrochemical etching

$$\text{Number of electron conducted during etching} = \sum_{t=24\text{ h}}^{e^-} It. \quad 6.24 \times 10^{18} \text{C}^{-1}$$

$$\text{Number of MAX phases unit cell} = \frac{m_{\text{MAX}}}{M_w(\text{MAX})} N_A$$

I = current; t = etching time; m_{MAX} = mass of MAX phases; $M_w(\text{MAX})$ = molecular weight of MAX phases;

N_A = Avogadro constant

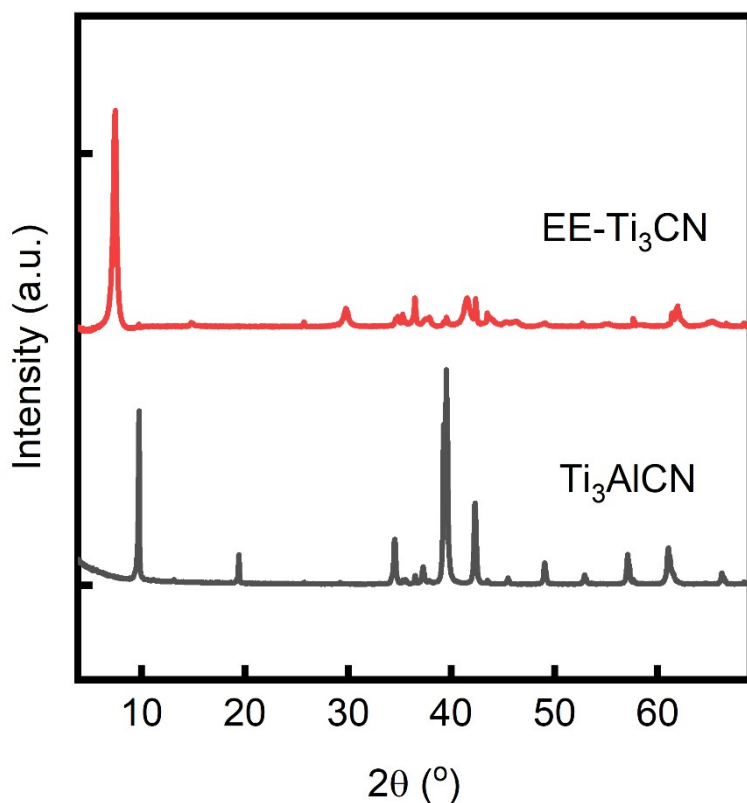


Figure S1. XRD spectrum of Ti_3AlCN precursor and electrochemically etched Ti_3CN . (Etching condition:

+1 V, 35 °C, 28 h.)

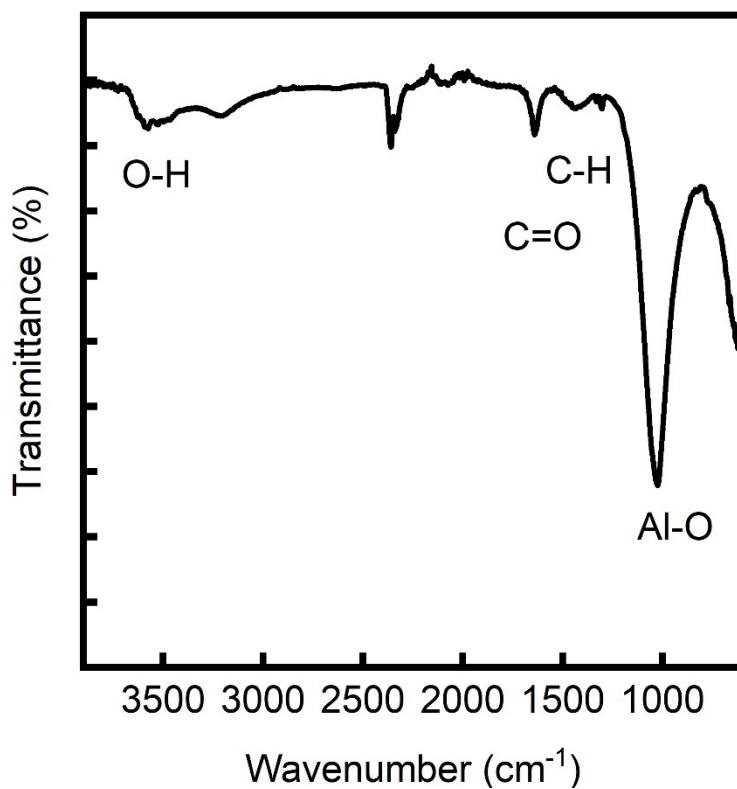


Figure S2. Infrared spectrum of the aluminium oxide precipitate after all HBF_4 electrolyte residue was evaporated.

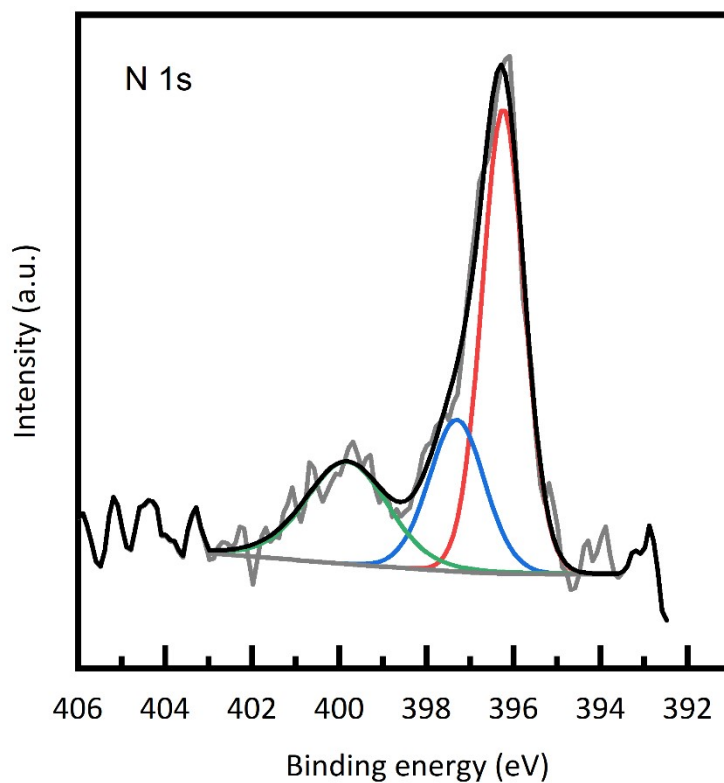


Figure S3. XPS N 1s spectrum of $\text{EE-Ti}_3\text{CN}$. Peaks located at 396.4, 397.1, 399.5, and 402.4 eV

are assigned for N-Ti, N-C, CH₃CN, and NH₄NO₃

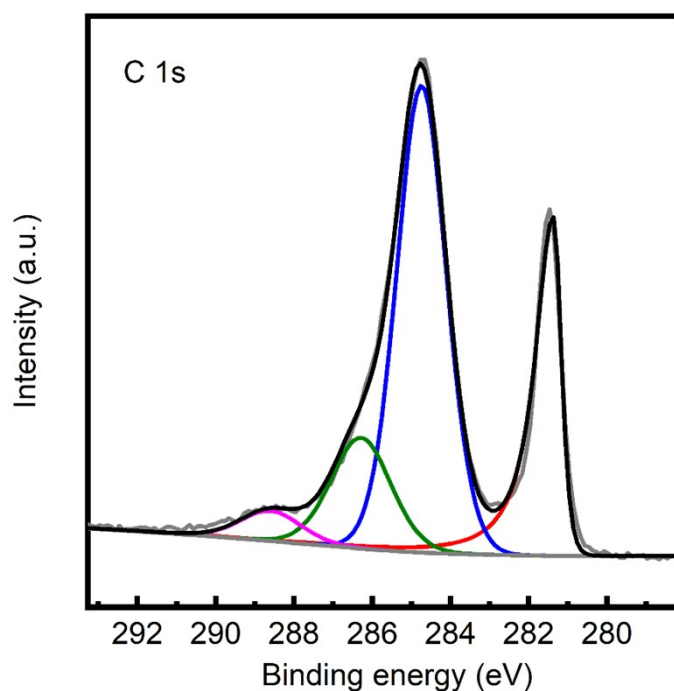


Figure S4. XPS C 1s spectrum of EE-Ti₃CN. peak located at 281.5, 284.7, 286.4, and 288.6 eV are assigned for X-Ti, C-C, C-O, and C=O, respectively.

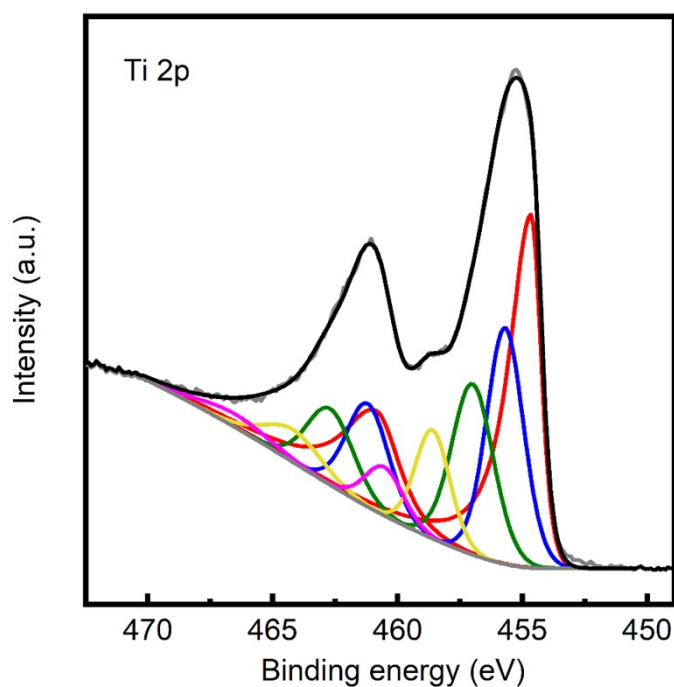


Figure S5. XPS Ti 2p spectrum of EE-Ti₃CN. Peaks located at 455.0(461.2), 455.9 (461.4), 457(462.7), 458.6(464.2), 460.2(466.2) eV are assigned for titanium metal in

the oxidation state of +1 to +3, TiO_2 , and $X-Ti-F$, respectively.



Figure S6. Photographs of Ti_3AlC_2 precursor, $EE-Ti_3C_2$ multilayer powder, dispersion of TMAOH treated $EE-Ti_3C_2$ in water.

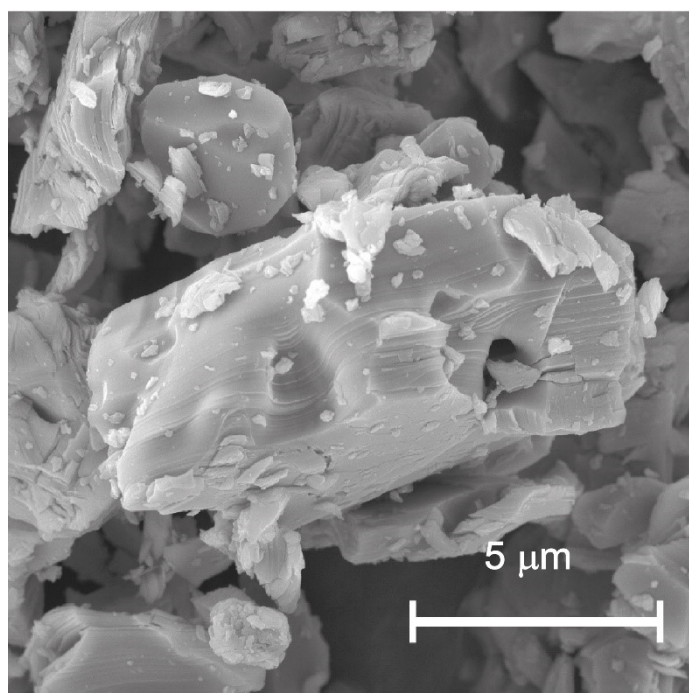


Figure S7. SEM images for Ti_3AlC_2 MAX phase.

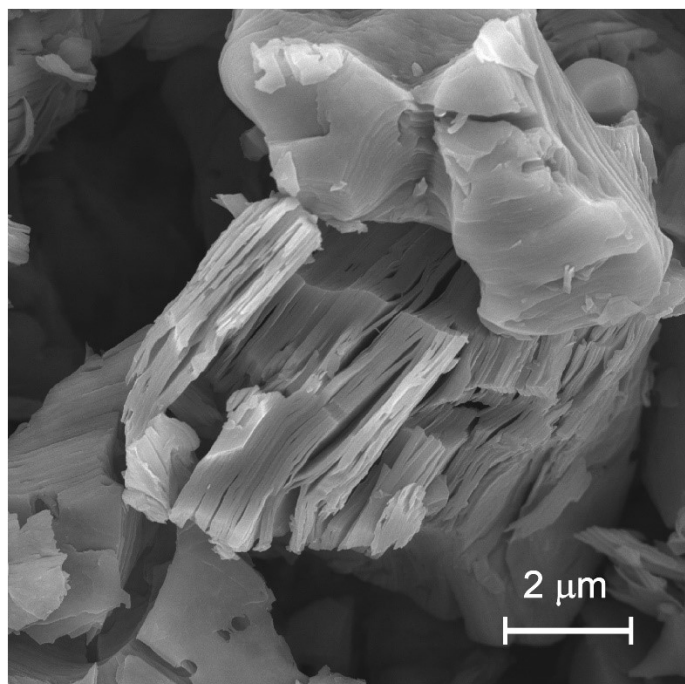


Figure S8. SEM image for EE-Ti₃CN.

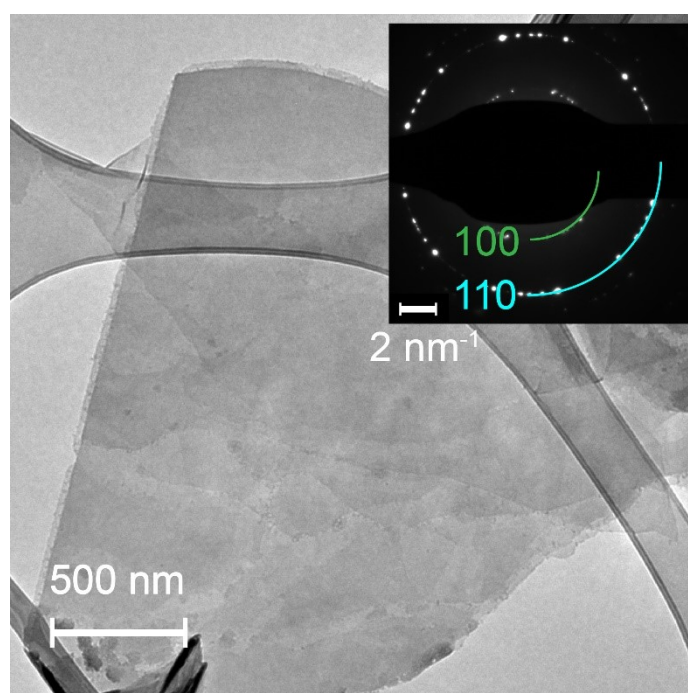


Figure S9. TEM image for EE-Ti₃CN delaminated flakes. (110) diffraction= 1.51 Å. (100) diffraction= 2.58 Å.